MPGD production 2016 at CERN MPT workshop

MPGD main projects done during 2016 at CERN MPT workshop

• <u>High Energy Phy</u>	<u>Completior</u>		
·SBS tracker	detector 600mm × 500mm	150 det	95%
SBS Tracker	detector 500mm × 400mm	50 det	100%
ALICE TPC	GEM 1.6m × 400mm	700 GEM	25%
·CMS GE1/1	GEM 1.2m \times 450mm	450 GEM	32%
BESIII	detector 600mm × 400mm	30 det	20%
SOLID	GEM 1.1m × 400mm	8 det	100%
CLAS 12	Micromegas 500mm × 500mm	30 det	90%
CBM	$GEM 1m \times 450mm$	100 GEMs	100%
BM@N Dubna	GEM detectors 1.8m × 0.6m	8 detectors	25%
Gbar	Micromegas 400mm × 400mm	20 detectors	10%

MPGD main projects done during 2016 at CERN MPT workshop

<u>Nucleur priysics/</u>	Geoscience/ NeuTrino	10 1 1 1	<u>completio</u>
·Mcube	Micromegas detectors	12 detectors	80%
•Astro Gamma	Micromegas TPC	3 detectors	60%
·Zitix	Micromegas TPC	3 detectors	100%
·Texat-P	Micromegas TPC	3 detectors	100%
·Panda X	Micro-BULK	9 detectors	100%
·TrexDM	Micro-BULK	3 detectors	50%
LSBB	Resistive Micromegas	2 detectors	100%

<u>MPGD main projects done during 2016 at CERN MPT workshop</u>

<u>R&D project</u>
Resistive Micromegas Muon large pitch low cost
ATLAS resistive Micromegas embedded resistors for high granularity high rate
CMS FTM multiple resistive well detectors for sub ns time resolution
CMS R-well Muon detectors
Embedded front end electronics in read-out boards
Embedded resistor uRwell for high rate application







largest GEM detector BM@N project 1.7m × 0.55 active area









largest u-Rwell detector GE1/1 active area



Industry situation

- TECHTRA:
 - GEM 10 cm × 10cm → regular delivery since 2 years
 - In 2016 we have subcontracted GEM to TECHTRA for a total amount slightly above 200 000 CHF
 - GEM 30cm x 30cm double mask \rightarrow Ok since 1 year
 - GEM 500mm x 600mm single mask → OK since a few months.
 - GEM 1.5m x 500mm already ordered
 - Participation to CMS GE1/1 being organized

- <u>Mecaronics (Korea)</u>
 - $-GEM 10cm \times 10cm \rightarrow OK$
 - Equipment ready for large size soon (1.2m x 0.5m).
- <u>Micro-Pack (India)</u>
 - $-GEM 10cm \times 10cm \rightarrow Ok$
 - Next steps to be defined
- Tech-Etch

– No information available

2 Main CERN's projects situation





CMS GE1/1 450 foils = 450 GEMS

ALICE TPC 350 Foils = 700 GEMs

CMS production : 450 foils

CMS productions should have started last quarter 2015

CMS production have effectively started April 2016 due to: -Layout definition -Base material problem The nominal expected rate was 240 foils/year (2 tech) The practical rate now is 200 foils/year due to -holidays impact -unpredicted illnesses Yield: 9 foils/Batch increases to 13 foils/batch



ALICE production : 350 foils

ALICE productions should have started mid 2015

Effective productions started June 2016 due to: -Layout modification The nominal expected rate was 216 foils/year (2 tech) The practical rate now is 140 foils/year due to -holidays impact -unpredicted illnesses -introduction of GEM cut and resistor soldering (main impact) Yield: 8 foils/batch increased to 12 foils/batch



2017 : Increase man power to

6 technicians (2 CMS, 4 ALICE) + TECHTRA + 1 CERN staff part time



Year	2016	2017	2018	
CERN/FSU (2p)	140	200	0	total 340
TECHTRA		110	0	total 110

CMS GE1/1



Year	2016	2017	2018	
CERN/FSU (4p)	90	240	0	total 330
CERN staff		20	0	total 20

ALICE TPC

B107





- Last information : B 107 ready end 2017
- Installation of new machines beginning 2018, no modification of the activity in 102: (2/3 months)
 - Etcher
 - Developer
 - Stripper
 - Jet pumice
 - Plating line
 - Desmearing line
 - Brown oxide line
 - Large dryer
 - NI/AU line
 - AU plating Bath
 - CU plating bath
 - Hoods etc
- Transfer plating activity (no stop)
- Transfer GEM missing equipment (1week)
 - 1 Laminator/Alcohol stripper/Electro-etching line/large exposure lamp
- Transfer the Photolithography equipment one by one (3 days stop per machine)
 - Laminators
 - LDI
 - UV lamps
 - ovens
- Transfer the CNC machines and test machines one by one (3 days stop per machine)
 - Driller
 - Router
 - AOI
 - Electrical tester
- Transfer Pressing equipment (3 days per equipment)
 - Large press
 - Std press
- Transfer photoplotter + developer (3 days stop)
- Transfer clean room equipment (1 week stop)
- Activity transferred mid 2018.
- Repair and transfer remaining equipment from 102

Thank you